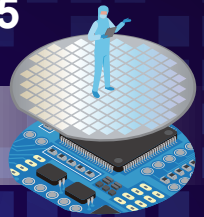


SEMICON[®] JAPAN

Dates 12/17 (Wed) to 19 (Fri) **Time** 10:00 to 17:00

Venue Tokyo Big Sight **CKD Booth** South 1-Hall S1505

Fine System Equipment Supporting the Semiconductor Market



Integrated Gas Supply System

IAGD

Air Operated Valve
AGD (high temperature/high durability)

Flow Rate Diagnostic Unit
TPB

Regulator
PGM

Gas-Facilities

Gas Supply

Deposition

Ion Implantation

Etching

Gas-Vacuum process

Pressure Control System
IAVB

Air Operated Valve
AVB

Proportional Control System
VEC-R

GAS control
VACUUM control

Air Operated Valve

AMD□□3R

Air Operated Valve (Manifold)
GAMD□□3R

Air Operated Valve (Metal-free)
AMD□1M

Manual Valve
MMD□03RN

Chemical-Facilities

Chemical Supply

Cleaning

Resist Coating

CMP

Chemical process

Electric Flow Control Valve
MNV

Pilot Operated Regulator
PMP

Fine Level Switch
KML

CHEMICAL control

Since the 1980s, we have contributed to higher precision and improved yields in semiconductor manufacturing processes through our "Accumulated technological capabilities," "Commitment to integrated production of core components," and "Thorough manufacturing process management."

Improving Productivity

Direct Acting 3-Port Valve, 3QR Series

For High-Speed Dispensing and Sorting

3QR High-Response Specification

Industry-Leading Level

Response Time ON: 2 ± 0.5 ms

(Initial value based on JIS B 8419: 2010 dynamic performance test)



For Battery-driven and Continuous Energization Applications

3QR Free power supply spec type

Industry First

Free power solenoid

High-Response Type DD Motor HD-4 Series

A new high-response model designed for high-speed tact time operation



For preventing valve malfunction

With interlock function MN3/4E0/MN3/4E00 Series

Implements an interlock function through individual power supply and shut-off

High speed 3D inspection equipment for advanced packaging

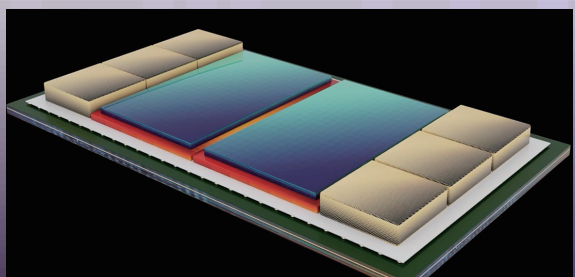
[Measurement Examples] Micro bump height, Cu pillars, wafer/substrate warpage, foreign matter

Features

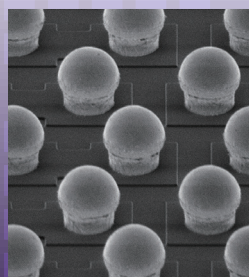


- High-speed measurement using CKD's proprietary (patented) optical system: 32 WPH
- High resolution: Horizontal resolution 1 μ m
- Compatible standards: SEMI S2, S8, CE

Measurement Examples



- Micro-bump height
- Cu Pillar



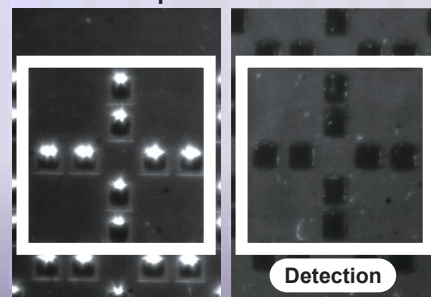
- Wafer and substrate Distortion
- Foreign matter

New Transparent Object Inspection System

[Measurement Examples] Flux inspection, TGV inspection

Flux Inspection

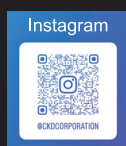
Inspection results



TGV Inspection



From front-end to mid- and back-end semiconductor processes, you will find hints to solve your challenges with CKD's total technical capabilities. Please feel free to visit our booth.



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Components Business Division
Sales Promotion Department